

RMP Process Samples

0.6 µm Standard Process

Monitor Device(s)

DS2401 C2

<i>Product</i>	<i>Rev</i>	<i>Product</i>	<i>Rev</i>	<i>Product</i>	<i>Rev</i>
DS12885	B1	DS12885	B1-C	DS12887	A2-C
DS1337	A2	DS1642	C1	DS1642	C1-M
DS1643	A6-AB	DS1643	A7-AB	DS1643	C1
DS1672	A3-2	DS1672	A3-3	DS1672	A3-3.
DS1672	A4-002	DS1672	A4-003	DS1672	A4-0;
DS1678	A3	DS1679	A4-A	DS1679	A4-B
DS1904	SA1	DS1921	A3	DS1921	A6
DS1921L	A3-F51	DS1921L	A3-F52	DS1921L	A6-F;
DS1921L	A6-F52	DS1921L	A6-F53	DS1990	G3-F
DS1990	G3-F50	DS1990	G4-F50	DS1990	H3-F.
DS1990	H3-F50	DS1990	J3-F30-	DS1990	J3-F;
DS21Q43	A3-A	DS2401	C1	DS2401	C2
DS2405	B1	DS2405	B2	DS2409	A1
DS2415	A1	DS2417	A1	DS2490	A5

0.6 μ m Old process

<i>Product</i>	<i>Rev</i>				
DS1374-18	A2	DS1374-3	A2	DS1374-33	A2
DS1375	A1	DS1482	A1	DS1500	A3-Y
DS2117M	C1	DS2118M	C1	DS2119M	C1
DS2125	A1	DS21348	C1	DS2148	C1
DS21554	C1	DS21Q554	C1	DS21Q59	A2
DS2411	A1	DS2740	A1	DS3904	A1
DS3905	A1				

0.6 μ m Capacitor

Monitor Device(s)

DS21352 A4

Product Rev

DS1722	A2	DS1722	A4	DS1775	A1
DS1775	A2	DS1921	B2	DS1921	B3
DS1921H	B1	DS1921H	B3	DS1921Z	B1
DS1921Z	B3	DS1963S	A5-F50	DS21348	A2
DS21348	B1	DS21352	A3	DS21352	A4
DS21352	B1	DS21352	B2	DS21354	A1
DS21354	A4	DS21354	B1	DS2148	A2
DS2148	B1	DS2149	A1	DS21552	A3
DS21552	A4	DS21552	B1	DS21554	A3
DS21554	A4	DS21554	B1	DS21600	A2
DS21600	A4	DS21602	A2	DS21602	A4
DS21604	A4	DS21610	A4	DS2196	A3
DS2196	A4	DS2196	A6	DS2197	A3
DS21Q352	A3	DS21Q352	A4	DS21Q352	B1
DS21Q352	B2	DS21Q354	A1	DS21Q354	A4
DS21Q354	B1	DS21Q50	A1	DS21Q552	A3
DS21Q552	A4	DS21Q552	B1	DS21Q554	A3
DS21Q554	A4	DS21Q554	B1	DS2421	A5
DS2890	A3				

0.6 μm Buried contacts w/silicided poly

<i>Product</i>	<i>Rev</i>				
DS5001	C3	DS5001	C4	DS5001	C5
DS5001	C6	DS5002	C1	DS5002	C4
DS5002	C5	DS5002	C6		

0.6 μm EPROM process

<i>Product</i>	<i>Rev</i>				
DS1981	D4	DS1981	D5	DS1982	D2
DS1982	D3	DS1982	D4	DS1982	D5
DS1985	B1	DS1985	B2	DS2450	A3
DS2501	C3	DS2501	C4	DS2502	C2
DS2502	C3	DS2502	C4	DS2503	B1
DS2503	B2	DS2505	B1	DS2505	B2
DS29020	A7-340	DS29022	A7-32E	DSQ0901-M	A1

0.6 μm Twin Gates (2 Tox's (1.2 μm only); Negative Zero Tempco Poly w/Capacitor

<i>Product</i>	<i>Rev</i>
DS21Q50	B2

0.6 μm PolySilicide

<i>Product</i>	<i>Rev</i>				
DS1954	B4-12	DS1954	B6-12	DS1954	B7-12
DS1954	B8-12	DS1954	B9-12	DS5240	A5
DS80CH11	A4	DS83C950	B8-12	DS83C950	B8-12
DS83C950	B9-12				

0.6 μm EPROM w/silicided poly(s)

<i>Product</i>	<i>Rev</i>
DS87C550	A9

0.6 μm Flash ETOX

<i>Product</i>	<i>Rev</i>
DS2118M	C1

0.6 μm E2PROM +Negative zero tempco poly + Capacitor

<i>Product</i>	<i>Rev</i>				
DS1077	C2	DS1077L	C2	DS1085	A2
DS1085L	A2	DS1110	B2	DS1110L	B2
DS1621	B3	DS1631	A3	DS1631	A4
DS1631A	A4	DS1721	C4	DS1731	A3
DS1731	A4	DS1820	B5	DS1820	B6
DS1820	B7	DS1822	B6	DS1822	B6-P
DS1822	B7	DS1847	C1	DS1848	C1
DS1851	A1	DS1920	B1	DS2720	A4
DS2760	C2	DS2761	A2	DS2763	A2

0.6 μ m E2PROM process

Monitor Device(s)

DS1100 A3

Product Rev

DS1002 A3

DS1135 A1

DS1100 A3

DS1135L A1

DS1100L B1

DS1682 A4

0.6 μ m Negative zero tempco poly

<i>Product</i>	<i>Rev</i>				
DS1050	A1-001	DS1050	A1-005	DS1050	A1-0
DS1050	A1-025	DS1052	A2-100	DS1830	B1-0
DS1830	B1-050	DS1831	A2	DS1831	A2-A
DS1831	A2-B	DS1831	B1	DS1831	B1-A
DS1831	B1-B	DS1831	B1-C	DS1831	B1-D
DS1831	B1-E	DS2117M	B2	DS2117M	B4
DS2118M	B1	DS2119M	B2	DS2119M	B4

0.6 μ m E2PROM w/ Capacitor Process

<i>Product</i>	<i>Rev</i>				
DS1847	B1	DS1848	B1	DS1852	A3
DS1961	A4	DS1961S	A4-F30	DS1961S	A4-F1
DS1973	A3	DS1973	B3	DS2432	A3
DS2433	A9	DS2436	C6	DS2436	C7
DS2438	A5	DS2438	A6	DS2760	A1-M
DS2760	B3	DS2770	A3	DSQ33G1-M	A
DSQ33G4	A	DSQ33G6	A		

0.6 μ m E2PROM process

<i>Product</i>	<i>Rev</i>				
DS1809	B2-010	DS1809	B2-050	DS1809	B2-10
DS1845	A2	DS1845	A2	DS1845	A2
DS1845	A2	DS1845	A2	DS1846	A1-D
DS1855	B1	DS1973	A2	DS2433	A8
DS2702	A5				

0.8 μ m Standard Process

Monitor Device(s)

DS1302 A4

Product Rev

DS1033	B2	DS1035	C1	DS1044	C1
DS1044	C2	DS1232	C1-L	DS1232	C2
DS1232	C2-L	DS12887	A2-B	DS1302	A3
DS1302	A4	DS1305	A4	DS1305	A4-A
DS1306	A2	DS1307	A3	DS1307	A4
DS1308	A1	DS1410	A1	DS1410	C
DS1410	E	DS1410	EGSI	DS1411	A-S0
DS1411	B-S09	DS1411	E	DS1411	F
DS1480	A2	DS1481	A1	DS1481	A3
DS1670	A2	DS1671	A4	DS1673	A2-3
DS1673	A2-5	DS1674	A1	DS1677	A1
DS1680	A1-3	DS1680	A1-5	DS1721	B3
DS1721	B4	DS1800	A1	DS1801	A2
DS1802	A2	DS1803	A2	DS1803	A2
DS1803	A2	DS1806	A1-10	DS1806	A1-10
DS1806	A1-100	DS1806	A1-100	DS1806	A1-50
DS1807	A1	DS1832	A2	DS1832	A3
DS1832	C2	DS1844	A1	DS1844	A1
DS1844	A2	DS1866	A1	DS1866	A2
DS1868	A4	DS1868	A4-A	DS1868	A4-B
DS1868	A4-C	DS1963	A1-F50	DS1963	A2-F:
DS1963	A3-F50	DS1992	E6-F50	DS1992	E7-F:
DS1993	E6-F50	DS1993	E7-F50	DS1996	B4-F:
DS21372	A2	DS2172	A2	DS21Q41	A1-B
DS2401	B2	DS2423	A3	DS2464	B4
DS24S02	A4	DS24S03	A4	DS4201	A4
DS4201	A5	DS56	A2	DS60	A2
DS75	A2	DS75	A3	DS75	A4
DS75	A5				

0.8 μm Old process

<i>Product</i>	<i>Rev</i>				
DS1065	A1	DS1065	A2	DS1073	A1
DS1073	A2	DS1075	A1	DS1075	A2
DS1075	A3	DS1175	A2		

0.8 μ m EPROM process

<i>Product</i>	<i>Rev</i>				
DS1023	B1	DS1023	B2	DS2406	A1
DS2406	A2	DS2407	A2	DS2407	A3
DS2407	A4	DS2502	B5	DS2502	B6
DS2503	A1	DS2505	A4	DS2505	A5
DS2505	A6	DS2506	A5	DS29020	A6-30
DS32KHZ	A6	DS32KHZ	A7	DS76KHZ	A6

0.8 μ m PolySilicide

<i>Product</i>	<i>Rev</i>				
DS80C310	A2	DS80CH10	B3	DS83C520	A3
DS83C520	A3				

0.8 μ m EPROM w/silicided poly(s)

Monitor Device(s)

DS87C520 A15-I

Product Rev

DS87C520 A15
DS87C520 A15-I

DS87C520 A15
DS87C530 A15

DS87C520 A15-I
DS87C530 A15-I

0.8 μm E2PROM process

<i>Product</i>	<i>Rev</i>
DS2436	A2

0.8 μm Negative zero tempco poly

<i>Product</i>	<i>Rev</i>				
DS1230	A1-W	DS1230	A1-Y	DS1230	B1-A
DS1230	B1-W	DS1230	B1-Y	DS1231	D3-A
DS1231	D3-B	DS1231	D3-C	DS1233	B2
DS1233	B2	DS1233	B2	DS1233	B2
DS1233	B2	DS1233	B2	DS1233	B2
DS1233	B2	DS1233	B2	DS1245	A1-V
DS1245	B1-A	DS1245	B1-Y	DS1249	B-A
DS1249W	B	DS1250	B1-A	DS1254	A-W
DS1254	A-Y	DS1258	A1-AB	DS1258	A1-V
DS1258	A1-Y	DS1258	B1-AB	DS1258	B1-Y
DS1258	C1-AB	DS1258	C1-Y	DS1265W	A
DS1270W	B	DS1312	A5	DS1314	A5
DS1321	A2	DS1321	A3	DS1323	A1
DS1345	A1-W	DS13D12	A5	DS13D14	A5
DS13D21	A3	DS1705	A3	DS1705	A4
DS1705	B1	DS1706	A3	DS1706	A3-L
DS1706	A4	DS1706	A4-L	DS1706	A4-P
DS1706	A4-R	DS1706	A4-S	DS1706	A4-T
DS1706	B1	DS1706	B1-L	DS1706	B1-P
DS1706	B1-R	DS1706	B1-S	DS1706	B1-T
DS1707	A3	DS1707	A4	DS1707	B1
DS1708	A3	DS1708	A4	DS1708	A4-R
DS1708	A4-S	DS1708	A4-T	DS1708	B1
DS1708	B1-R	DS1708	B1-S	DS1708	B1-T
DS1780	A4	DS1810	A6	DS1810	A6
DS1810	A6	DS1810	A7	DS1810	A7
DS1810	A7	DS1811	A6	DS1811	A6
DS1811	A6	DS1811	A7	DS1811	A7
DS1811	A7	DS1812	A6	DS1812	A6
DS1812	A6	DS1812	A7	DS1812	A7
DS1812	A7	DS1813	A5	DS1813	A5
DS1813	A5	DS1813	A6	DS1813	A6

DS1813	A6	DS1814	B2	DS1814	B3
DS1814	B3	DS1814	B3	DS1814	B3
DS1814	B3	DS1814	B3	DS1814	B4
DS1814	B4	DS1814	B4	DS1814	B4
DS1814	B4	DS1814	B4	DS1814	B5
DS1814	B5	DS1814	B5	DS1814	B5
DS1814	B5	DS1814	B5	DS1815	A6
DS1815	A6	DS1815	A6	DS1815	A7
DS1815	A7	DS1815	A7	DS1816	A6
DS1816	A6	DS1816	A6	DS1816	A7
DS1816	A7	DS1816	A7	DS1817	A6
DS1817	A6	DS1817	A6	DS1817	A7
DS1817	A7	DS1817	A7	DS1818	A5
DS1818	A5	DS1818	A5	DS1818	A6
DS1818	A6	DS1818	A6	DS1819	B1
DS1819	B1	DS1819	B1	DS1819	B1
DS1819	B1	DS1819	B1	DS1819	B1
DS1819	B1	DS1819	B1	DS1819	B2
DS1819	B3	DS1819	B3	DS1819	B4
DS1819	B5-A10	DS1819	B5-A20	DS1819	B5-B1
DS1819	B5-B10	DS1819	B5-B20	DS1819	B5-C
DS1819	B5-C10	DS1819	B5-C20	DS1819	B6-A1
DS1834	A2-A	DS1834	A3-A	DS1836	A4
DS2105	A3	DS2105	B1	DS2105	B2
DS2106	A1	DS2106	A2	DS2106	B1
DS2109	A5	DS2109	A7	DS2109	B1
DS2110	A1	DS2110	B3	DS2114	B2
DS2114	C1	DS2118M	A3	DS2118M	A4
DS21S07	B1-A	DS21S07	B2-A	DS21S07	C1-A
DS21T05	A3	DS21T06	A2	DS21T07	A3
DS21T11	A2	DS3816	A-C512	DS3832	C-C3
DS38432	A	DS38464	A		

0.8 μ m E2PROM process

Monitor Device(s)

DS1620 D1 DS1621 A7

Product Rev

DS1620	D1	DS1621	A5	DS1621	A7
DS1623	A3	DS1624	A4	DS1624	A6
DS1629	A2	DS1720	A3	DS1804	A6
DS1804	A6	DS1804	A6	DS1821	A3
DS1971	A2	DS1971	A3	DS2430	A2-A
DS2430	A3-A	DS2430	A4-A	DS2434	D1
DS2435	B2	DS2435	B4	DS2437	A1
DS2437	A2	DS24S34	A2		

1.2 μm Standard Process

<i>Product</i>	<i>Rev</i>				
DS1000	E3	DS1004	E1	DS1012	B1
DS1040	A2	DS1202	A2	DS1205	B2
DS1205	B4	DS1205	B5	DS1205	B7
DS1245	A1-A	DS1245	A1-Y	DS1272	B2
DS1273	B2	DS1285	C1	DS1285	C2
DS12887	A2	DS1336	A1	DS1360	B1
DS1380	B2	DS1384	A1	DS1386	A1
DS14285	A3	DS14287	A3	DS1464	A1
DS1602	A1	DS1608	B4	DS1609	A1
DS1610	A3	DS1632	A1-H	DS1632	A5
DS1640	A1	DS1644	B2	DS1646	A2
DS1646	B1	DS1646	B2	DS1646	G
DS1647	A1	DS1648	A3	DS1710	A4
DS1710	A5	DS1921L	A3-F51	DS1921L	A3-F:
DS1963	A3-F50	DS1963S	A5-F50	DS1991	E5-F:
DS1991	E5-F50	DS1991	E6-F50	DS1991	E7-F:
DS1991	E8-F50	DS1994	E1-F50	DS1994	E2-F:
DS1994	E2-F50	DS1994	E3-F50	DS1994	E4-F:
DS1994	E4-F50	DS2012	A3	DS2013	A1
DS2016	A2	DS2068	A3	DS2102	C3
DS2130	A1	DS2143	A1	DS2143	A3
DS2164	A1	DS2165	B1	DS2223	B2
DS2224	B2	DS2225	A1	DS2401	A2
DS2401	A3	DS2404	B5	DS2404	C1
DS2405	A2	DS2405	A3	DS2414	A1
DS9502	A1	DS9503	A1		

1.2 μm Old process

<i>Product</i>	<i>Rev</i>		
DS2009	A1/2	DS2009	A3

1.2 μm Buried contacts w/silicided poly

<i>Product</i>	<i>Rev</i>				
DS2252	Q	DS5001	A4	DS5001	B3
DS5002	A3	DS5002	B3	DS5002	B3
DS5002	B3-M	DS5002	B4	DS5002	B4-M
DS5002	M2-M	DS5002	M3-M	DS50C302	B2-M
DS50C302	M1-M				

1.2 μm EPROM process

<i>Product</i>	<i>Rev</i>				
DS1045	A2	DS1688	A3	DS1689	A5
DS1691	A3	DS1693	A5	DS2502	A6

1.2 μ m Implanted Poly 1

Monitor Device(s)

DS1267 A1

Product Rev

DS1267 A1
DS1666 A1-010

DS1267 A2
DS1666 A1-100

DS1267 A2
DS1666 A2-010

1.2 μm Negative zero tempco poly

<i>Product</i>	<i>Rev</i>		
DS2107A	A5	DS2107A	A6

1.2 μm Tera-ohm resistor

<i>Product</i>	<i>Rev</i>		
DS1589	B1	DS1589	B3

1.2 μ m E2PROM process

<i>Product</i>	<i>Rev</i>				
DS1620	C2	DS1625	A1	DS1669	B3-A
DS1669	B3-A	DS1669	B3-A	DS1669	B3-B
DS1669	B3-C	DS1820	A2	DS1867	A3
DS1867	C1	DS1867	C1	DS1867	C1
DS1867	C1+	DS1867	C1+	DS1867	C1+
DS1869	A2	DS1869	A3-10	DS1869	A3-11
DS1869	A3-50	DS1920	A1	DS1920	A1-E
DS2435	A5				

1.2 μm Zero tempco poly

<i>Product</i>	<i>Rev</i>				
DS1233	A3-300	DS1233	A3-500	DS1233	A5-300
DS1233	A5-500	DS1233	A5-500	DS1233	A5-500
DS1233	A5-550	DS1833	A1	DS1833	A2
DS1833	A2-B	DS2107	A4		

1.5 μm Standard Process

<i>Product</i>	<i>Rev</i>
DS2141A	A1

1.5 μm Resistor (poly1 or poly2)

<i>Product</i>	<i>Rev</i>				
DS1020	B5	DS1020	B5	DS1021	B5

2.0 μm Standard Process

<i>Product</i>	<i>Rev</i>				
DS2010	B1	DS2011	B1	DS2167	A4

2.0 μm Buried contacts

<i>Product</i>	<i>Rev</i>		
DS5000	D6	DS5000	D6-T

2.0 μm Pfield

<i>Product</i>	<i>Rev</i>				
DS1003	A2	DS1005	A2	DS1007	A1
DS1007	A2	DS1010	B1	DS1013	B1
DS1200	D1	DS1201	D1	DS1204	F1
DS1236	A1-A	DS1236	A5	DS1238	A1-A
DS1238	A5	DS1239	A5	DS1239	A6
DS1259	C2	DS1260	C2	DS1283	A3
DS1284	A3	DS1285	B3	DS1286	A3
DS1359	C3	DS2175	D1	DS2176	D4
DS2180A	B3	DS2181A	A2	DS2182	A1-A
DS2182	D1	DS2186	C4	DS2187	C4
DS2187	C7	DS2188	C1		

2.0 μm Resistor (poly1 or poly2)

<i>Product</i>	<i>Rev</i>		
DS1207	E2	DS1207	E2-N

3.0 μm Standard Process

<i>Product</i>	<i>Rev</i>				
DS1206	B1	DS1214	A4	DS1215	D4
DS1216	na-B	DS1216	na-C	DS1216	na-D
DS1216	na-E	DS1216	na-F	DS1216	na-H
DS1218	D1	DS1220	A1-Y	DS1222	B1
DS1225	A1-Y	DS1232	C1	DS1234	C1
DS1291	B1	DS1292	B2		

3.0 μm POCL3 reFlow (3um only); FLASH E2PROM (all other tech. numbers)

<i>Product</i>	<i>Rev</i>				
DS1210	C1	DS1211	B1	DS1212	B1
DS1213	na-B	DS1213	na-C	DS1213	na-D
DS1220	A1-A	DS1221	C1	DS1225	A1-A
DS1230	A1-A	DS1231	C1		

5.0 μm Standard Process

<i>Product</i>	<i>Rev</i>				
DS1808	A2	DS229	A3	DS232	B3-A
DS275	A2	DS276	A2		

5.0 μm Negative zero tempco poly

<i>Product</i>	<i>Rev</i>		
DS2108	B1	DS2108	B7